

Docket Number: 081468-0306527  
Client Reference: P-0382.010-US

*IPR*  
PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re the Application of

ARNO JAN BLEEKER

Group Art Unit: 2881

Application No.: 10/715,116

Examiner: Unassigned

Filed: November 18, 2003

Confirmation No.: 3978

For: LITHOGRAPHIC APPARATUS AND DEVICE MANUFACTURING METHOD

February 1, 2005

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents  
P. O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Pursuant to 37 C.F.R. 1.56, the attention of the Patent and Trademark Office is hereby directed to the following U.S. patent application(s):

Examiner's Initials	First Inventor	Application No.	Filing Date	Enclosed
	STREEFKERK et al. (081468-0309796)	10/850,451	05/21/2004	<input checked="" type="checkbox"/> Specification <input checked="" type="checkbox"/> Drawings <input checked="" type="checkbox"/> Other: stamped receipt card
	MULKENS (081468-0310380)	10/890,389	07/14/2004	<input checked="" type="checkbox"/> Specification <input checked="" type="checkbox"/> Drawings <input checked="" type="checkbox"/> Other: stamped receipt card
	STREEFKERK et al. (081468-0309421)	10/844,575	05/13/2004	<input checked="" type="checkbox"/> Specification <input checked="" type="checkbox"/> Drawings <input checked="" type="checkbox"/> Other: stamped receipt card
	SUWA et al. (Reissue Application of U.S. Patent No. 6,191,429 B1)	10/367,910	02/19/2003	<input checked="" type="checkbox"/> Specification <input checked="" type="checkbox"/> Drawings <input type="checkbox"/> Other: stamped receipt card

\*The Examiner's initials adjacent a citation indicates he/she has considered the cited application relative to the subject application.

It is respectfully requested that these applications and the art cited therein during examination be expressly considered during the prosecution of this application and be made of record in this application. The identification of the above U.S. patent applications is not to be construed as a waiver of secrecy as to those applications now or upon issuance of the present application as a patent.

**PLEASE DO NOT PRINT** the above information on the patent which results from this application.

Consideration of each listed application is earnestly solicited since unpublished patent applications are contemplated as IDS material; see the exception in Rule 98(a)(2)(iii) and note the penultimate sentence of MPEP 609.

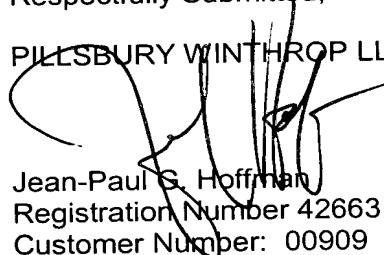
Further, in keeping with MPEP 609, subsec. C(2), 2nd para., line 10 to end of the paragraph (especially note lines 18-25) **PLEASE RETURN A COPY OF THIS LETTER** with the Examiner's initials adjacent each above listing so that applicant will know that each listed application has been considered as required by PTO policy.

**Secondly**, please consider each document which is listed on the attached Form PTO-1449 and return a copy of that form with the Examiner's initials adjacent each citation, a copy of each document enclosed except for any U.S. patents and published patent applications. It is respectfully requested that these documents listed on the Form PTO-1449 be expressly considered during the prosecution of this application, and that the documents be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

This Information Disclosure Statement is being filed before the mailing date of the first Office Action on the merits in the present application. No certification or fee is required.

Respectfully Submitted,

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FORM PTO-1449 (modified)  
 To: U.S. Department of Commerce  
 (PW FORM PAT-1449)  
 Patent and Trademark Office



Atty. Dkt. No.	M#	Client Ref.
	0306527	P-0382.010-US

**INFORMATION DISCLOSURE STATEMENT  
BY APPLICANT**

Date: February 1, 2005

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Applicant: Arno J. BLEEKER

Appln. No.: 10/715,116

Filing Date: November 18, 2003

Examiner: Unknown Group Art Unit: 2881

**U.S. PATENT DOCUMENTS**

Examiner's Initials*	Document Number	Date MM/YYYY	Name (Family Name of First Inventor)	Class	Sub Class	Filing Date (if appropriate)
AR	4,390,273	06/1983	LOEBACH et al.	355	125	
BR	6,236,634 B1	05/2001	LEE et al.	369	112	
CR	2002/0020821 A1	02/2002	VAN SANTEN et al.	250	492	
DR	2004/0075895 A1	04/2004	LIN	359	380	
ER	2004/0109237 A1	06/2004	EPPEL et al.			
FR	2004/0119954	06/2004	KAWASHIMA et al.	355	30	
GR	2004/0125351	07/2004	KRAUTSCHIK	355	53	
HR						
IR						
JR						

**FOREIGN PATENT DOCUMENTS**

	Document Number	Date MM/YYYY	Country	Inventor Name	English Abstract		Translation Readily Available	
					Enclosed	No	Enclose	No
KR	JP 07-132262	05/1995	Japan	HIRAKAWA et al.		X		
LR	JP 58-202448	11/1983	Japan	KAWAMURA et al.		X		
MR	WO 2004/019128	03/2004	PCT	OMURA et al.		X		X
NR	WO 03/077037	09/2003	PCT	ROSTALSKI et al.		X		X
OR	WO 03/077036	09/2003	PCT	SCHUSTER		X		
PR	DD 206 607	02/1984	GERMANY	WESTPHAL et al.			X	
QR	DD 221 563	04/1985	GERMANY	PFORR et al.			X	
RR	JP 11-176727	07/1999	JAPAN	SHIRAISHI		X		
SR	JP 2000-058436	02/2000	JAPAN	FUJISHIMA et al.		X		

**OTHER (Including in this order Author, Title, Periodical Name, Date, Pertinent Pages, etc.)**

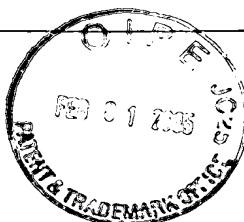
TR	S. OWA et al., "Update on 193nm immersion exposure tool", Litho Forum, International SEMATECH, Los Angeles, January 27-29, 2004, Slide Nos. 1-51.		
UR	H. HATA, "The Development of Immersion Exposure Tools", Litho Forum, International SEMATECH, Los Angeles, January 27-29, 2004, Slide Nos. 1-22.		
VR	T. MATSUYAMA et al., "Nikon Projection Lens Update", SPIE Microlithography 2004, 5377-65, March, 2004.		
WR	"Depth-of-Focus Enhancement Using High Refractive Index Layer on the Imaging Layer", IBM Technical Disclosure Bulletin, Vol. 27, No. 11, April 1985, p. 6521.		
XR	A. SUZUKI, "Lithography Advances on Multiple Fronts", EEdesign, EE Times, January 5, 2004.		
YR	B. LIN, "The $k_3$ coefficient in nonparaxial $\lambda/NA$ scaling equations for resolution, depth of focus, and immersion lithography, J. Microlith., Microfab., Microsyst. 1(1):7-12 (2002).		
ZR			

Examiner

Date Considered:

\*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.

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	AAR					
	BBR					

**FOREIGN PATENT DOCUMENTS**

	Document Number	Date MM/YYYY	Country	Inventor Name	English Abstract		Translation Readily Available	
					Enclosed	No	Enclose	No
CCR	WO 2004/053950 A1	06/2004	PCT	OWA		X		
DDR	WO 2004/053951 A1	06/2004	PCT	MAGOME et al.		X		
EER	WO 2004/053952 A1	06/2004	PCT	MAGOME et al.		X		
FFR	WO 2004/053953 A1	06/2004	PCT	NEI et al.		X		
GGR	WO 2004/053954 A1	06/2004	PCT	NEI et al.		X		
HHR	WO 2004/053955 A1	06/2004	PCT	HIRUKAWA et al.		X		
IIR	WO 2004/053956 A1	06/2004	PCT	NAGASAKA et al.		X		
JJR	WO 2004/053957 A1	06/2004	PCT	HIDAKA et al.		X		
KKR	WO 2004/053958 A1	06/2004	PCT	MIZUTANI et al.		X		
LLR	WO 2004/053959 A1	06/2004	PCT	SHIRAI		X		
MMR	WO 2004/053959 A2	06/2004	PCT	GRAUPNER		X		
NNR	WO 2004/055803 A1	07/2004	PCT	VAN SANTEN		X		X
OOR	WO 2004/057589 A1	07/2004	PCT	NEIJZEN et al.		X		X
PPR	WO 2004/057590 A1	07/2004	PCT	VAN SANTEN et al.		X		X
QQR	JP 2004-193252	07/2004	Japan	Not Available		X		
RRR	0 605 103 A1	07/1994	EP	TAKAHASHI		X		X

**OTHER (Including in this order Author, Title, Periodical Name, Date, Pertinent Pages, etc.)**

SSR	Search Report for European Application No. 03257194.5, dated March 1, 2004.			
TTR				
UUR				
VVR				
WWR				
XXR				
YYR				

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